

ABSTRACT OF THE DISCLOSURE

In order to provide an electron microscope which enables the operator to position the field of view easily and accurately on a target fault, the electron microscope for observing a surface or inside of a semiconductor wafer or a mask for exposing a semiconductor pattern for faults and/or foreign objects, is provided comprising a function of loading measurement data of coordinates or sizes of faults or objects which were observed by another wafer or mask inspecting apparatus, moving the field of view of the electron microscope to the area where said fault or object exists, and displaying the coordinates of faults or objects which were obtained by another wafer or mask inspecting apparatus, the field of view of the electron microscope and its vicinity, a function of a pointing device switch which moves the field of view of the electron microscope to a position which is pointed to by a pointer on said display, and a function of changing the display as said field of view moves.